

ABSTRACT OF THE DISCLOSURE

~~Disclosed is a~~ A fabricating method for a system including a plurality of processing apparatuses connected to each other by means of an inter-apparatus transporter, wherein ~~one group of~~. The semiconductor wafers are processed in the processing apparatuses and ~~other group of wafers are~~ transported to specified processing apparatuses ~~for a~~ in different time intervals from (T_0+T) to a time T_0 ; and another ~~group of wafers are processed and the remaining group of wafers are transported for a time interval from (T_0+T) to (T_0+2T) . Since processing apparatuses can receive at least one of works from the inter-apparatus transporter for a time interval T min, the distribution of works from the transporter to processing apparatus is completed for the time interval T min. The transporter is emptied for each time interval T min, and works are unloaded to the emptied transporter, which makes easy the scheduling, control and management of the transporting of a plurality of works in the fabricating system. Moreover, that are set to N times a unit time interval. ~~since~~ Since the fabricating system including~~

includes processing apparatuses ~~is~~ and an inter-apparatus
transporter that are periodically controlled at time intervals
related to a cycle-unit time ~~T_{min}~~, intervals related to a
unit time, the scheduling of a plurality of works can be made
~~easy,~~ efficiently to enhance the level of optimization, thus
improving the productivity.